

ent Application of

SASAKI

Attv. Ref.: 1035-243

Serial No. 09/487,259

Group: 2814

Filed: January 19, 2000

Examiner: A. Mai

For: METHOD OF MANUFACTURING SEMICONDUCTOR

DEVICE USING CHEMICAL ETCHING

April 14, 2003

Assistant Commissioner for Patents Washington, DC 20231

Sir:

## INFORMATION DISCLOSURE STATEMENT

As suggested by 37 C.F.R. 1.97, the undersigned attorney brings to the attention of the United States Patent and Trademark Office the references listed on the attached form PTO-1449, a copy of each of which is enclosed. This is not to be construed as a representation that a search has been made or that no better prior art exists, or that a reference is relevant or prior art merely because cited.

The Examiner is requested to initial the attached form PTO-1449 and to return a copy of the initialed document to the undersigned as an indication that the attached references have been considered and made of record.

The undersigned attorney of record hereby certifies under 37 C.F.R. § 1.97(e) that each item of information referenced herein and attached hereto was first cited in any communication from a foreign patent office in a counterpart foreign application not more

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than three months prior to the filing of this Information Disclosure Statement. A copy of the communication dated April 1, 2003 is enclosed. An English-language translation of the communication is enclosed to comply with the requirement for a concise explanation of non-English language information.

Pursuant to Rule 37 C.F.R. § 1.97(c), a fee of \$180.00 as specified in Rule 17(p) is attached. If there is any shortage in the fee, please charge the deposit account of Nixon & Vanderhye, Account No. 14-1140.

Respectfully submitted,

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